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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Confirmation No.: 7420

Takaei SASAKI et al.

Group Art Unit: 1746

Serial No.: 10/706,944

Examiner: Michail Kornakov

Filed: November 14, 2003

Attorney Docket No.: 101136-00103

For: METHOD AND APPARATUS FOR DRY-ETCHING HALF-TONE
PHASE-SHIFT FILMS, HALF-TONE PHASE-SHIFT PHOTOMASKS
AND METHOD FOR THE PREPARATION THEREOF, AND
SEMICONDUCTOR CIRCUITS AND METHOD FOR THE
FABRICATION THEREOF

AMENDMENT UNDER 37 CFR §1.111

Mail Stop Amendment

Director for the U.S. PTO

P.O. Box 1450

Alexandria, VA 22313-1450

Date: June 7, 2004

Sir:

In reply to the outstanding Office Action dated April 22, 2004, please amend the
application as shown on the following pages: